ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention

METHOD AND SYSTEM TO COMPENSATE FOR LAMP INTENSITY DIFFERENCES IN A PHOTOLITHOGRAPHIC INSPECTION TOOL

Application Number:

10/749887

8895

Confirmation Number:

First Named Applicant:

David Dixon

Attorney Docket Number:

CT004

Art Unit:

1756

Examiner:

Search string:

(3749496 or 4806776 or 5039868 or 5335293 or 5581074 or 5835220 or 5917588

or 5943437 or 5995217 or 6064759 or 6078386 or 6151064 or 6337488 or 6356347

or 6376852 or 6515742 or 6570650 or 20020009220 or 20030011761 or

20030059103 or 20030086080).pn

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass	
त्रिय	1	3749496	1973-07-31	Hietanen et al.		356	73	
	2	4806776	1989-02-21	Kley		250	560	
\Box	3	5039868	1991-08-13	Kobayashi et al.		250	572	
	4	5335293	1994-08-02	Vannelli et al.	Α	382	17	
	5	5581074	1996-12-03	Yoshida	Α	250	205	
\Box	6	5835220	1998-11-10	Kazama et al.	Α	356	369	
	7	5917588	1999-06-29 Addiego		Α	356	237	
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V	17	6570650	2003-05-27	Guan et al.	B1	356	237.4	

US Published Applications

Note: Applicant is not required to submit a paper copy of cited US Published Applications

init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass	
DR	1	20020009220	2002-01-24	Tanaka	A1	382	145	
	2	20030011761	2003-01-16	Gilat-Bernshtein et al.	A1	356	237.4	
\sqcap	3	20030059103	2003-03-27	Shiomi et al.	A1	382	144	
V	4	20030086080	2003-05-08	Guan et al.	A1	356	237.1	

Signature

Examiner Name	Date
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Sheet 1 (A) of 1 SUBSTITUTE FORM 100-1449 (MODIFIED) TRADEN **U.S. DEPARTMENT OF COMMERCE** ATTY. DOCKET NO. SERIAL NO. PATENT AND TRADEMARK OFFICE CT/004 10/749,887 INFORMATION DISCLOSURE **APPLICANT** STATEMENT BY APPLICANT Dixon et al. FILING DATE **GROUP** (Use several sheets if necessary) (37 CFR 1.98(b)) December 31, 2003 1756 **U.S. PATENT DOCUMENTS** ISSUE FILING DATE EXAMINER IF APPROPRIATE INITIAL PATENT NUMBER PATENTEE CLASS **SUBCLASS** DATE A.A A.B A.C A.D A.E A.F A.G A.H A.I A.J A.K FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS DOCUMENT **PUBLICATION COUNTRY OR TRANSLATION** PATENT OFFICE NUMBER DATE **CLASS SUBCLASS** (YES/NO) A.L JP3013850 01/22/1991 Japan JP20243 JP7060135B No 26C A.M A.N A.O A.P A.Q OTHER DOCUMENTS (Including Author, Title, Date, Place of Publication) A.R A.S

EXAMINER: Initial if citation considered, whether or not in conformance. Draw line through citation only if not in conformance and not considered. Include a copy of this form with next communication to applicant.

DATE CONSIDERED

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Substitute Disclosure Form (PTO-1449)